EAST Search History

Ref#	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	861	(257/E21.09,E21.461).OCLS.	US-PGPUB; USPAT	OR	OFF	2009/06/18 11:24
L2	2403705	@ad>"20021003" or @rlad>"20021003"	US-PGPUB; USPAT	OR	OFF	2009/06/18 11:24
L3	233	1 not 2	US-PGPUB; USPAT	OR	OFF	2009/06/18 11:24
SI	216	438/41.ccls.	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:15
S2	9269	epitaxial\$3 and (CVD or "chemical vapor deposition") and (nitrogen or noble)	US-PGPUB; USPAT	OR	OFF	2007/06/24 08:22
S3	856049	@ad>"20021003" or @rlad>"20021003"	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:13
S4	22	S1 and S2	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:13
S5	17	S4 not S3	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:13
S6	450	epitaxial\$3 with IV	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:15
S7	1	S5 and S6	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:16
S8	74	S2 and S6	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:16
S9	52	S8 not S3	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:16
S10	62	epitaxial\$3 with (CVD or "chemical vapor deposition") with (nitrogen or noble)	US-PGPUB; USPAT	OR	OFF	2007/06/24 08:32
S11	3	S6 and S10	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:29
S12	0	S11 not S3	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:29
S13	41	S10 not S3	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:31
S14	17305	(nitrogen or noble) with carrier	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:32
S15	8	S13 and S14	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:32
S16	192	438/44.ccls.	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:35
S17	20	S2 and S16	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:35
S18	13	S17 not S3	US-PGPUB; USPAT	OR	OFF	2006/03/14 18:35
S19	156	438/222.ccls.	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:14
S20	9269	epitaxial\$3 and (CVD or "chemical vapor deposition") and (nitrogen or noble)	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:13
S21	856049	@ad>"20021003" or @rlad>"20021003"	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:13

S22	12	S19 and S20	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:13
S23	10	S22 not S21	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:14
S24	94	438/226.ccls.	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:15
\$25	7	S20 and S24	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:14
S26	7	\$25 not \$21	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:14
S27	198	438/413.ccls.	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:15
S28	22	S20 and S27	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:15
S29	21	\$28 not \$21	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:15
S3 0	133	438/442.ccls.	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:15
S31	16	\$20 and \$30	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:15
S32	16	S31 not S21	US-PGPUB; USPAT	OR	OFF	2006/03/15 15:15
S33	10	epitaxial\$3 with (CVD or "chemical vapor deposition") with nitrogen with carrier	US-PGPUB; USPAT	OR	OFF	2007/06/24 08:22
S34	1430917	@ad>"20021003" or @rlad>"20021003"	US-PGPUB; USPAT	OR	OFF	2007/06/24 08:22
S35	3	S33 not S34	US-PGPUB; USPAT	OR	OFF	2007/06/24 08:22
S36	10	epitaxial\$3 with (CVD or "chemical vapor deposition") with (nitrogen or "N.sub.2") with carrier	US-PGPUB; USPAT	OR	OFF	2007/06/24 08:32
S37	15	epitaxial\$3 and(CVD or "chemical vapor deposition") and (nitrogen or "N.sub.2") and carrier	FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/06/24 08:33
S3 8	1	("6,379,419").PN.	US-PGPUB; USPAT	OR	OFF	2007/06/26 13:17
S39	0	(SGe or "silicon germanium") with (CVD or chemical vapor deposition) with source with nitrogen with carrier	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:16
S40	1575251	@ad>"20021003" or @rlad>"20021003"	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:16
S41	3	(SGe or "silicon germanium") with (CVD or chemical vapor deposition) with nitrogen with carrier	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:19
S42	2	S41 not S40	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:17
S43	0	(SGe or "silicon germanium") with epitaxial \$2 with (CVD or chemical vapor deposition) with nitrogen with carrier	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:19
S44	1	(SGe or "silicon germanium") with epitaxial \$2 with (CVD or chemical vapor deposition) with nitrogen	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:20
S45	1022	(SGe or "silicon germanium") with epitaxial \$2 with (CVD or chemical vapor deposition)	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:21

S46	0	(SGe or "silicon germanium") with epitaxial \$2 with (CVD or chemical vapor deposition) with ("N.sub.2")	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:20
S47	309	S45 not S40	US-PGPUB, USPAT	OR	OFF	2007/10/13 18:21
S48	336	CVD with nitrogen with carrier	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:21
S49	0	S47 and S48	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:21
S50	657395	nitrogen	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:21
S51	0	((SiGe or "silicon germanium") with epitaxial\$2 with (CVD or chemical vapor deposition)) same nitrogen same carrier	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:22
S52	11	((SiGe or "silicon germanium") with epitaxial\$2 with (CVD or chemical vapor deposition)) same nitrogen	US-PGPUB; USPAT	OR	OFF	2007/10/13 18:22
S53	3	S52 not S40	US-PGPUB; USPAT	OR	OFF	2007/10/13 19:05
S54	1139	Antireflective with materials	US-PGPUB; USPAT	OR	OFF	2007/10/13 19:05
S55	0	(SGeC or (silicon with germanium with carbon)) with epitaxial\$2 with (CVD or chemical vapor deposition) with ("N. sub.2")	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:08
S56	81	(SGeC or (silicon with germanium with carbon)) with epitaxial\$2 with (CVD or chemical vapor deposition") with (""N. sub.2""")	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:24
S57	1637842	@ad>"20021003" or @rlad>"20021003"	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:11
S58	16	S56 not S57	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:11
S59	O	(SGeC or (silicon with germanium with carbon)) with epitaxial\$2 with (CVD or "chemical vapor deposition") with ("""N. sub.2""" or nitrogen)	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:15
S60	О	(SIGeC or (silicon with germanium with carbon)) with epitaxial\$2 with (CVD or "chemical vapor deposition") with ("N. sub.2" or nitrogen)	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:15
S61	О	(SGeC or (silicon with germanium with carbon)) with epitaxial\$2 with (CVD or "chemical vapor deposition") with (nitrogen)	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:19
S62	o	(SGeC or (silicon with germanium with carbon)) with epitaxial\$2 with (CVD or "chemical vapor deposition") same (nitrogen)	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:20
S63	0	(SGeC or (silicon with germanium with carbon)) with epitaxial\$2 with ((CVD or "chemical vapor deposition") same (nitrogen))	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:20
S64	0	(SGeC or (silicon with germanium with carbon)) with epitaxial\$2 with ((CVD or "chemical vapor deposition") same ("N. sub.2" or nitrogen))	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:21

S65	8	(SGeC or (silicon with germanium with carbon)) with CVD with ("N.sub.2" or nitrogen)	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:21
S66	4	S65 not S57	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:21
S67	8	(SGeC or (silicon with germanium with carbon)) with (CVD or "chemical vapor deposition") with ("""N.sub.2""" or nitrogen)	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:28
S68	4	S67 not S57	US-PGPUB; USPAT	OR	OFF	2007/12/05 16:46
S69	9	(SGeC or (silicon with germanium with carbon)) with (CVD or "chemical vapor deposition") with ("N.sub.2"or nitrogen)	US-PGPUB; USPAT	OR	OFF	2008/06/01 12:06
S70	1868403	@ad>"20021003" or @rlad>"20021003"	US-PGPUB; USPAT	OR	OFF	2008/06/01 12:07
S71	4	S69 not S70	US-PGPUB; USPAT	OR	OFF	2008/06/01 12:07
S72	90	(SiGeC or (silicon with germanium with carbon)) same (CVD or "chemical vapor deposition") same ("N.sub.2" or nitrogen)	US-PGPUB; USPAT	OR	OFF	2008/06/01 12:08
S73	10	(SGeC or (silicon with germanium with carbon)) same (CVD or "chemical vapor deposition") same epitaxial\$2 same ("N. sub.2"or nitrogen)	US-PGPUB; USPAT	OR	OFF	2008/06/01 12:09
S74	5	S73 not S70 not S71	US-PGPUB; USPAT	OR	OFF	2008/06/01 12:09
S75	198	("2514055" "3117022" "3225820" "3390033" "3551213" "3770499" "3786359" "3806380" "3893219" "39003636" "3901423" "391757" "3946334" "3951757" "3946334" "3951757" "3943909" "4005340" "403416" "4053333" "407439" "4107350" "4108751" "4116751" "4116751" "4116751" "4116751" "4121341" "4244348" "4252087" "4255208" "4274004" "43452841" "44952620" "427601" "424404" "43452841" "4486309" "42505683" "4376125" "4412688" "4452642" "4486309" "4500563" "4500	US-PGPUB; USPAT; USOCR	OR	OFF	2008/06/01 12:11

		"5344524" "5354381" "5362671" "5363603" "5368710" "5370765" "5374564" "5376560" "5377031"	· · · · · · · · · · · · · · · · · · ·		***************************************	
		"5404679" "5405460" "5411592" "5413679" "5445680" "5436801" "5443681" "5445681" "5436901" "5475514" "5476981" "5480042" "5475514" "5546911" "559620" "5558716" "5559043" "5569620" "5558716" "5559043" "5569620" "55613881" "5559043" "5569620" "55613881" "5575914" "575921" "5710077" "57759914" "5763219" "5773022" "5804066" "5821158" "5783600" "5827751" "5804560" "5824595" "5909627" "5820764" "58582897" "5909627" "5907070" "5862897" "5909627" "5907070" "5938377" "5904207" "601579" "6013563" "601367" "6020252" "6033324" "6014911" "6077383" "6159624" "6120957" "6150239" "6159624" "6191007" "6214701" "6225192" "6224631", PN. OR				
S76	14	(SGeC or (silicon with germanium with carbon)) same (("N.sub.2"or nitrogen) with carrier)	US-PGPUB; USPAT	OR	OFF	2008/06/01 12:12
S77	o	S76 not S70	US-PGPUB; USPAT	OR	OFF	2008/06/01 12:12
S78	2096	(SGeC or (silicon with germanium with carbon)) same (("N.sub.2"or nitrogen) samecarrier)	US-PGPUB; USPAT	OR	OFF	2008/06/01 12:12
S79	33	(SGeC or (silicon with germanium with carbon)) same (("N.sub.2"or nitrogen) same carrier)	US-PGPUB; USPAT	OR	OFF	2008/06/01 12:12
S80	11	S79 not S70	US-PGPUB; USPAT	OR	OFF	2008/06/01 12:12
S81	3	(SiGeC with epitaxial\$3) with nitrogen	US-PGPUB; USPAT	OR	OFF	2008/06/09 09:53
S82	1878976	@ad>"20021003" or @rlad>"20021003"	US-PGPUB; USPAT	OR	OFF	2008/06/09 09:53
S83	2	S81 not S82	US-PGPUB; USPAT	OR	OFF	2008/06/09 09:53
S84	79	(SiGe or "silicon germanium") with epitaxial \$2 with ("SiH.sub.4" with "GeH.sub.4")	US-PGPUB; USPAT	OR	OFF	2008/07/30 15:26
S85	1947708	@ad>"20021003" or @rlad>"20021003"	US-PGPUB; USPAT	OR	OFF	2008/07/30 15:27
S86	25	S84 not S85	US-PGPUB; USPAT	OR	OFF	2008/07/30 15:29
S87	337	((SGe or "silicon germanium") with epitaxial\$2 with (CVD or chemical vapor deposition)) same ("500" or "550" or "600" or "525" or temperature)	US-PGPUB; USPAT	OR	OFF	2008/10/28 16:32
S88	2074000	@ad>"20021003" or @rlad>"20021003"	US-PGPUB; USPAT	OR	OFF	2008/10/28 16:32
S89	100	S87 not S88	US-PGPUB; USPAT	OR	OFF	2008/10/28 16:35

S90	12	[((SiGe or "silicon germanium") with epitaxial\$2 with (CVD or chemical vapor deposition)) same ("500" or "550" or "600" or "525" or temperature) same (nitrogen or "N sub 2")	US-PGPUB; USPAT	OR	OFF	2008/10/28 16:38
S91	1	S90 not S88	US-PGPUB; USPAT	OR	OFF	2008/10/28 16:38
S92	131	((SiGe or "silicon germanium") with epitaxial\$2 with (CVD or chemical vapor deposition)) same ("500" or "550" or "600" or "525" or temperature) and (nitrogen or "N sub 2")	US-PGPUB; USPAT	OR	OFF	2008/10/28 16:39
S93	39	S92 not S88	US-PGPUB; USPAT	OR	OFF	2008/10/28 16:39
S94	2396257	@ad>"20021003" or @rlad>"20021003"	US-PGPUB; USPAT	OR	OFF	2009/06/16 13:31
S95	1097	(438/41,44,222,226,413,442).CQLS.	US-PGPUB; USPAT	OR	OFF	2009/06/16 13:32
S96	785	S95 NOT S94	US-PGPUB; USPAT	OR	OFF	2009/06/16 13:32
S97	86	epitaxial\$3 with (CVD or "chemical vapor deposition") with nitrogen	US-PGPUB; USPAT	OR	OFF	2009/06/16 13:33
S98	2514	SiGeC	US-PGPUB; USPAT	OR	OFF	2009/06/16 13:33
S99	4	S97 and S98	US-PGPUB; USPAT	OR	OFF	2009/06/16 13:33
S100	1	S99 not S94	US-PGPUB; USPAT	OR	OFF	2009/06/16 13:33
S101	12	epitaxial\$3 with (CVD or "chemical vapor deposition") with nitrogen with carrier	US-PGPUB; USPAT	OR	OFF	2009/06/16 13:34
S102	98	(SGeC or (silicon with germanium with carbon)) with epitaxial\$2 with (CVD or chemical vapor deposition") with (""N. sub.2""")	US-PGPUB; USPAT	OR	OFF	2009/06/16 13:34
S103	17	epitaxial\$3 with (CVD or "chemical vapor deposition") with nitrogen	USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2009/06/16 13:34

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